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REPLY UNDER 37 C.F.R § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1764

PATENT
5480-00200/OP99140-US



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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Kim

Serial No. 09/287,602

Filed: April 7, 1999

For: GAS SCRUBBER FOR TREATING
THE GAS GENERATED DURING
THE SEMICONDUCTOR
MANUFACTURING PROCESS

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Group Art Unit: 1764
Examiner: Varcoe, F.

Atty. Dkt. No. 5480-00200

I hereby certify that this correspondence is being deposited
with the U.S. Postal Service with sufficient postage as First
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11/20/01
Date

Kevin L. Daffer

AMENDMENT; RESPONSE AFTER FINAL REJECTION
PURSUANT TO 37 CFR § 1.116

Box: AF
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

RECEIVED
JAN 22 2002
TC 1700

This paper is submitted in response to the Office Action dated September 13, 2001 to
further highlight reasons why the application is in condition for allowance.

Please amend the case as follows:

In the Claims:

Please replace claims 1, 6, 7, and 15 with the amended claims below. A "marked-up"
version of each amendment is included in **Attachment A**.